

Notice of References Cited	Application/Control No. 10/632,698	Applicant(s)/Patent Under Reexamination STAPLE ET AL.	
	Examiner Brian K Talbot	Art Unit 1762	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,824,910	10-1998	Last et al.	73/715
	B	US-6,525,352	02-2003	Muller et al.	257/252
	C	US-6,616,853	09-2003	Staple et al.	216/2
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	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

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	U	Ashruf et al., "galvanic porous silicon formation without external electrodes, Sensors and Actuators (74) 1999, pp. 118-122.
	V	Gennissen et al. "Sacrificial oxide etching compatible with aluminum metallization", 1997 International Conference on Solid-State sensors and Actuators, ppg. 225-228
	W	Bustillo et al., "Surface Micromachining for Microelectrochemical Systems", Proceeding of the IEEE, vol. 86, no. 8, August 1998 pp. 1552-1574.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.